A Matching Based Decomposer for Double Patterning Lithography

Yue Xu and Chris Chu

Electrical and Computer Engineering

Iowa State University

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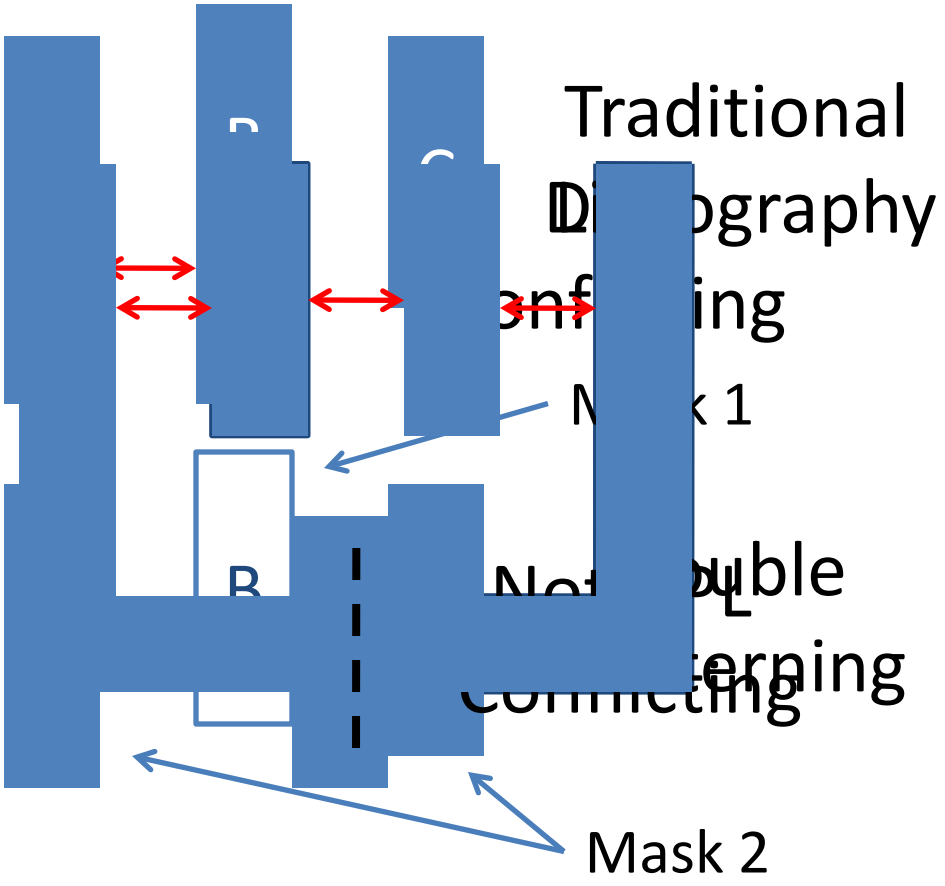
Outline

- Problem Formulation
- Previous Work
- Algorithm Flow
- Planar Graph Proof
- Face Merging Based Formulation
- Decomposition Algorithm
- Experiment

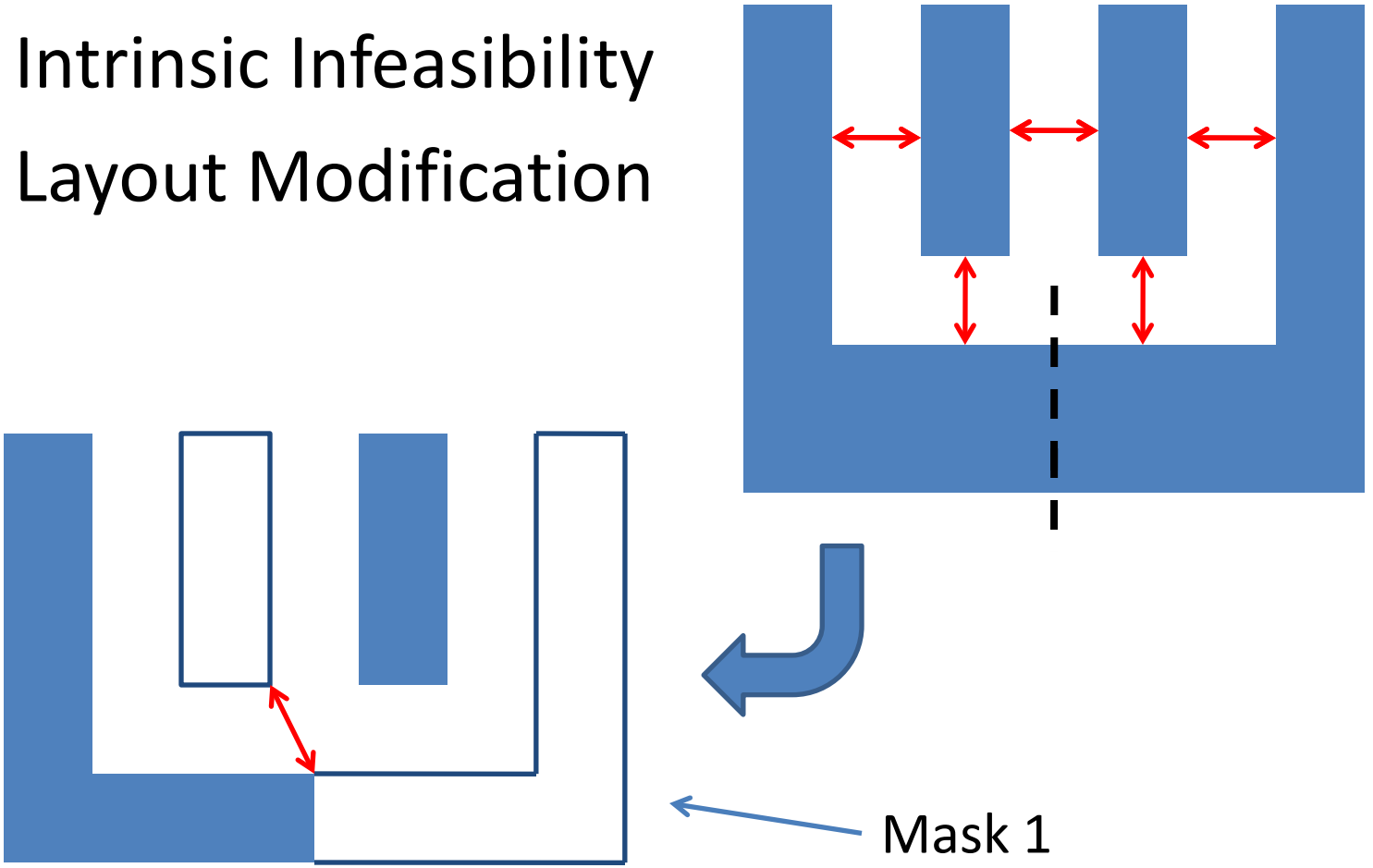
Double Patterning Lithography

- Double Patterning: two masks
- DPL Conflict
- DPL Infeasibility:
- Stitches



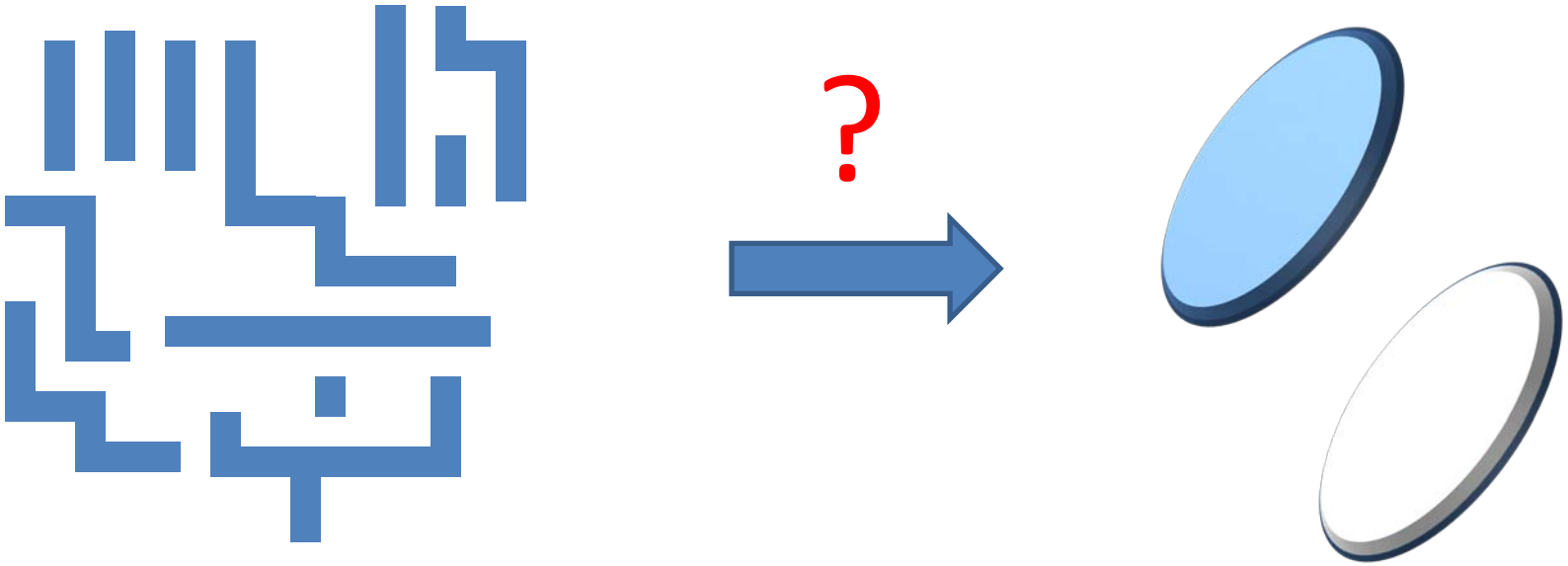
Double Patterning Lithography

- Intrinsic Infeasibility
- Layout Modification



DPL Decomposition Problem

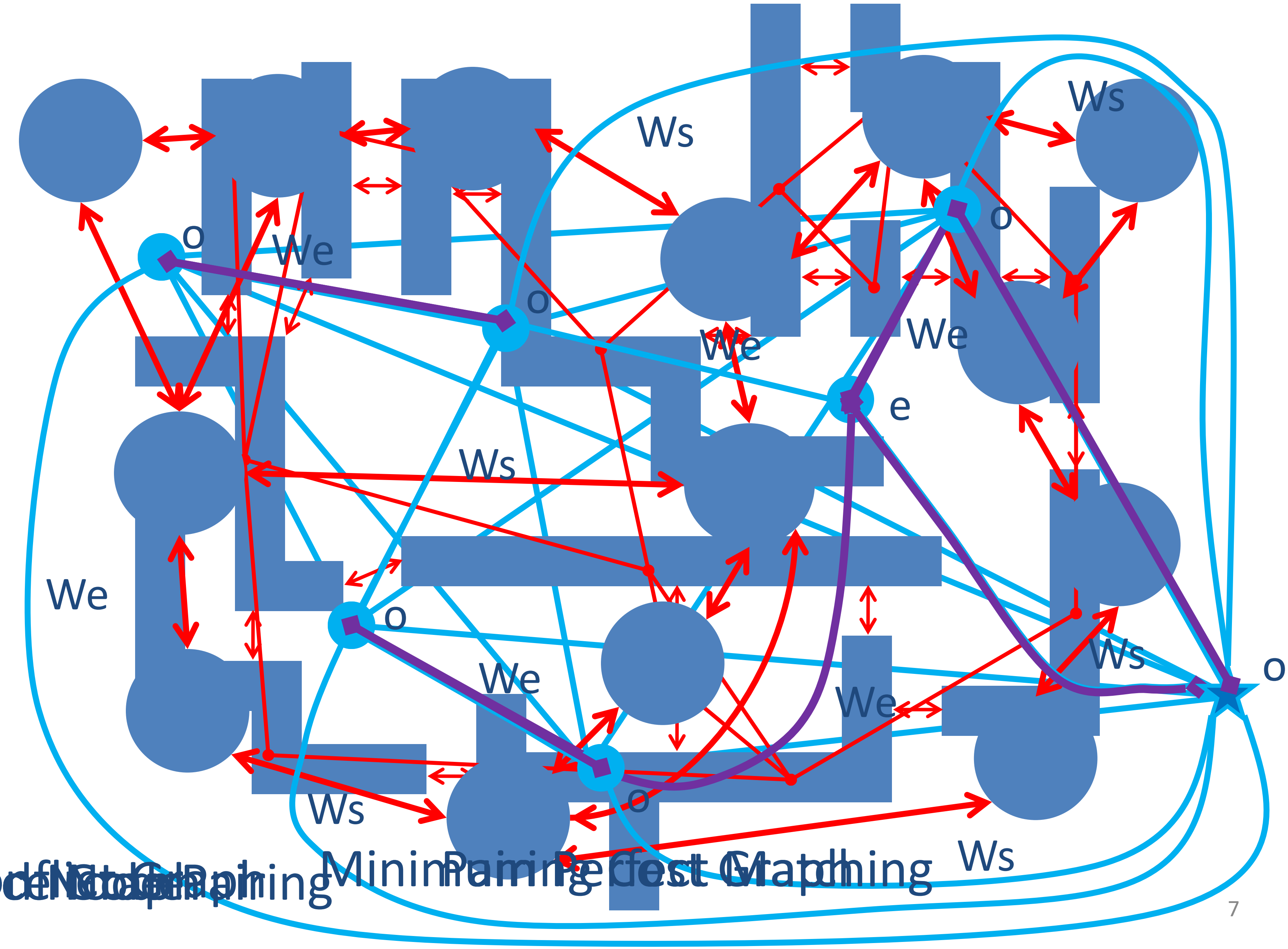
- Objective: To assign patterns on one layer to two masks and resolve every non-intrinsic infeasibility with minimum number of stitches



Recent Decomposers

- Model Based Decomposer:
  - optical simulation
  - too slow for current complex and large-scale layout
- Rule Based Decomposer:
  - Heuristics that greedily slice and assign patterns
  - Pre-slice patterns and use ILP to select mask assignment for sliced patterns, Kahng ICCAD 2008, Yuan ISPD 2009

Algorithm Flow



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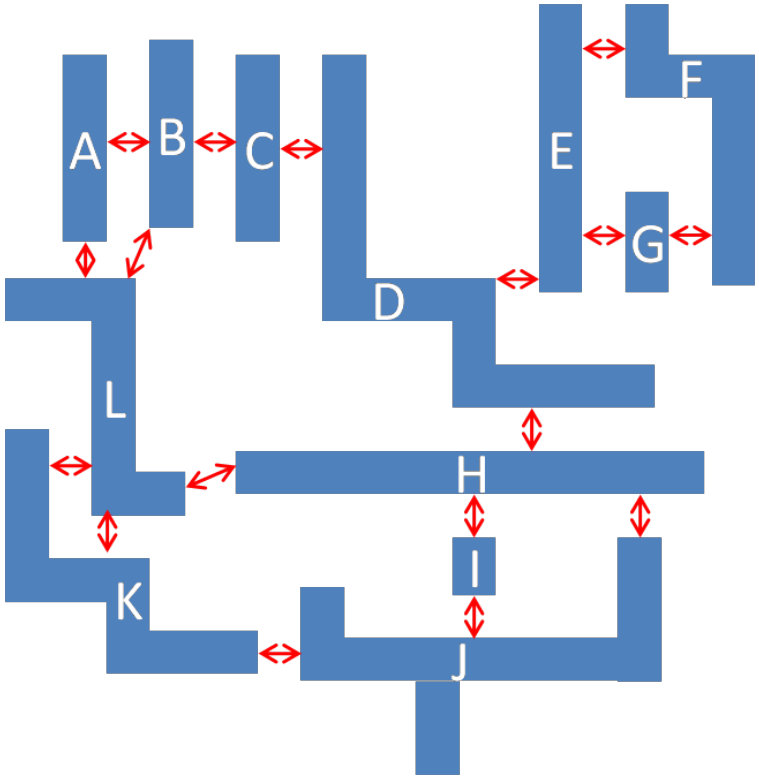
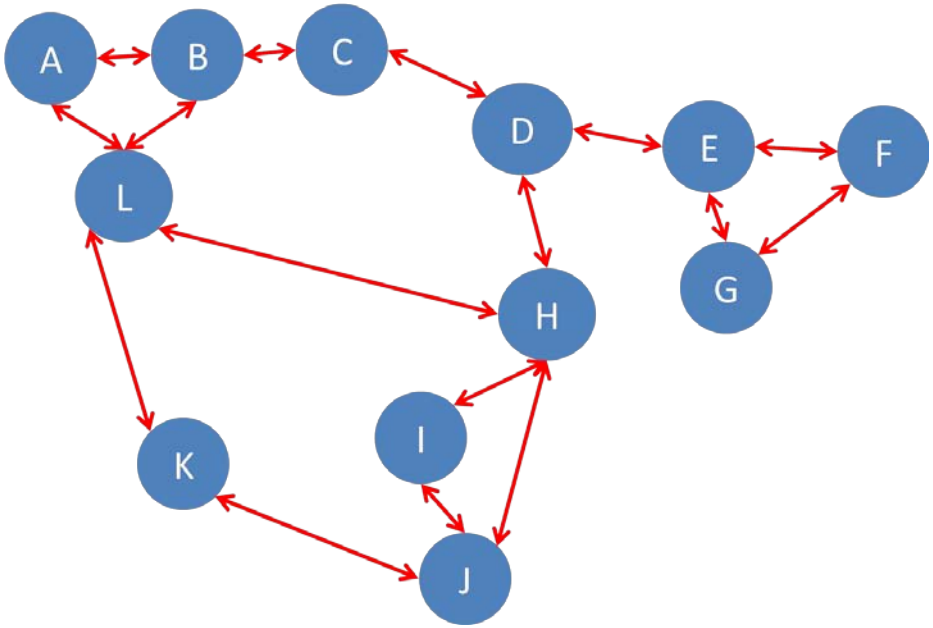
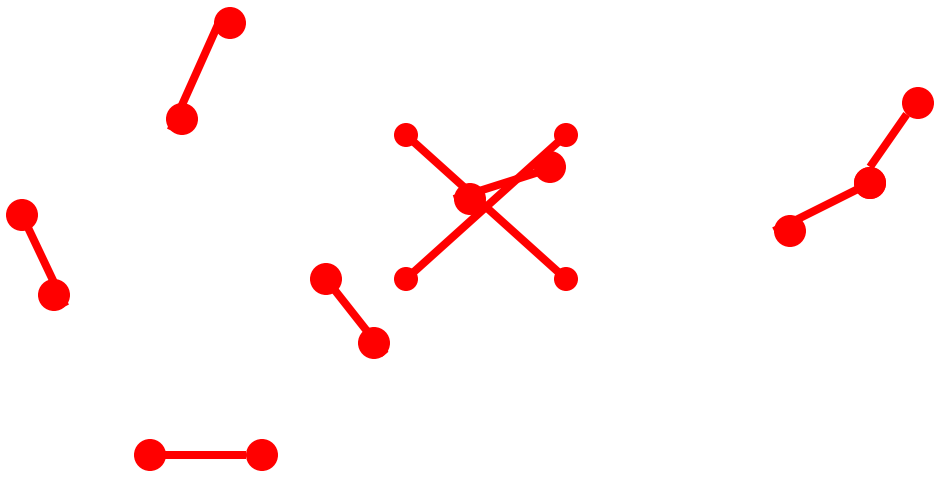
Conflict Graph





Planarity Of Conflict Graph

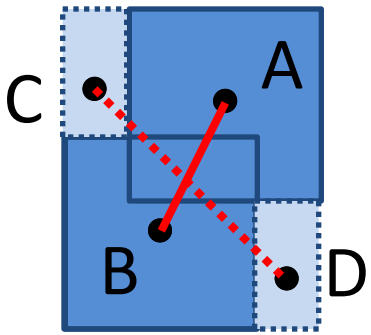
- Lemma 1: Crossing does not exist



Manhattan Distance: DPL Threshold $\leq 2\times$ Min Spacing

Euclidian Distance: DPL Threshold $\leq \sqrt{2}\times$ Min Spacing

Proof for Lemma 1



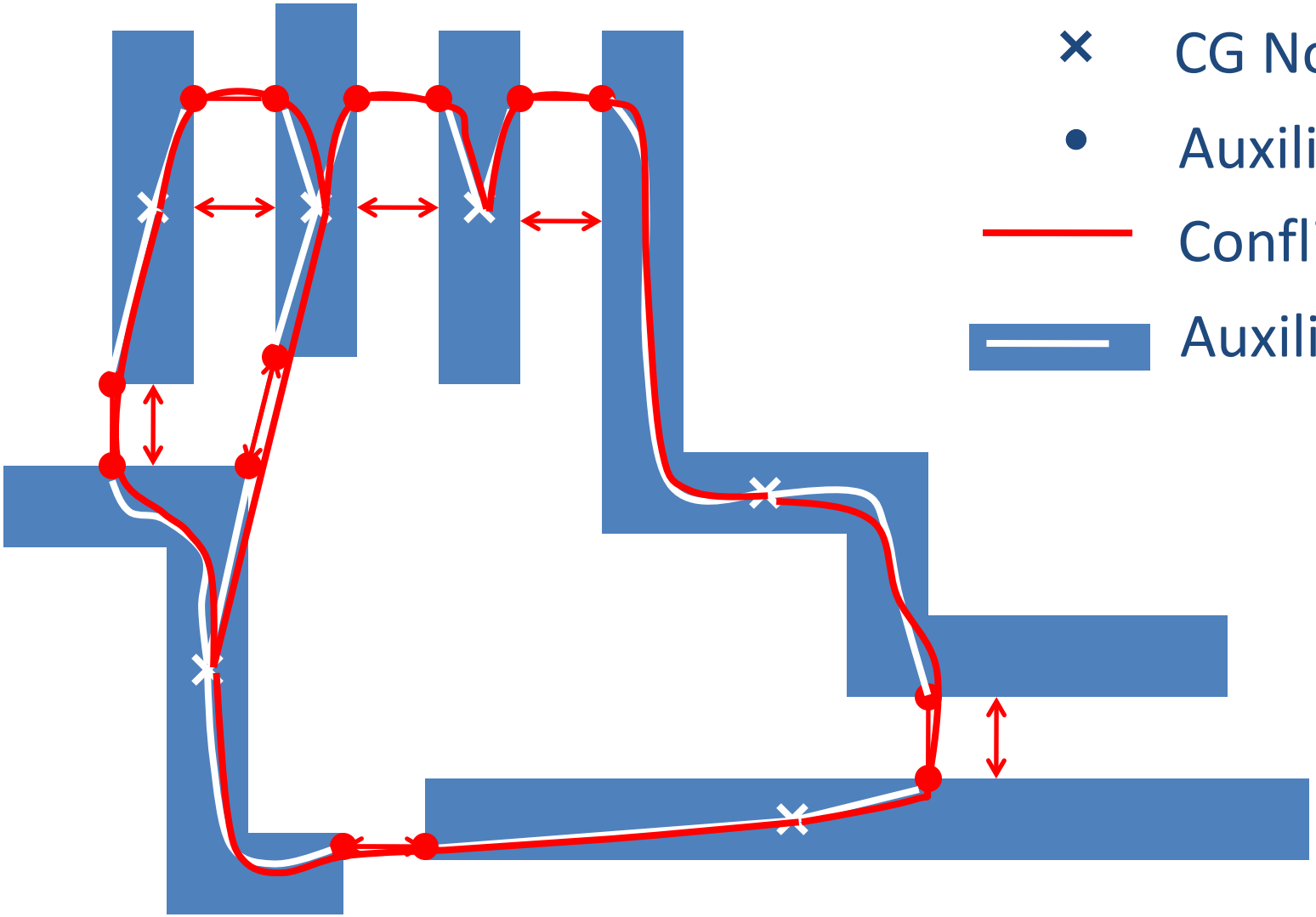
$$x_A - x_B + y_A - y_B < t$$

$$x_C \leq x_A - s$$
$$y_C \geq y_B + s$$
$$x_D \geq x_B + s$$
$$y_D \leq y_A - s$$

$$\begin{aligned} MD(C,D) &= x_D - x_C + y_C - y_D \\ &\geq x_B - x_A + 2s + y_B - y_A + 2s \\ &> 4s - t \end{aligned}$$

$$MD(C,D) < t \Rightarrow t \not\geq 2s$$

Planar Embedding



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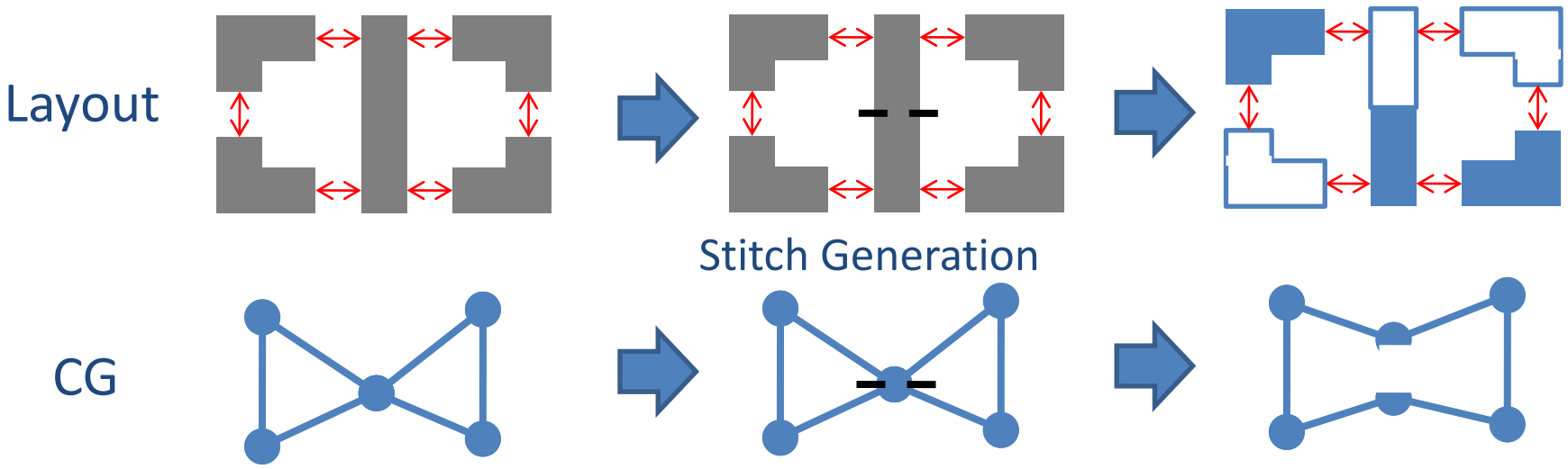
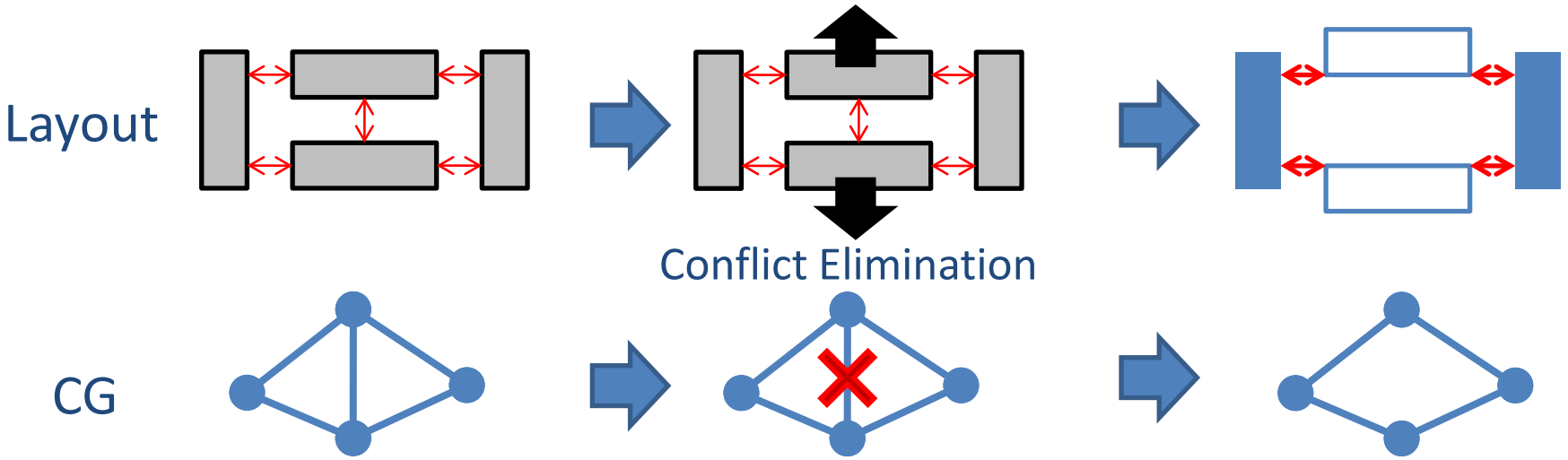
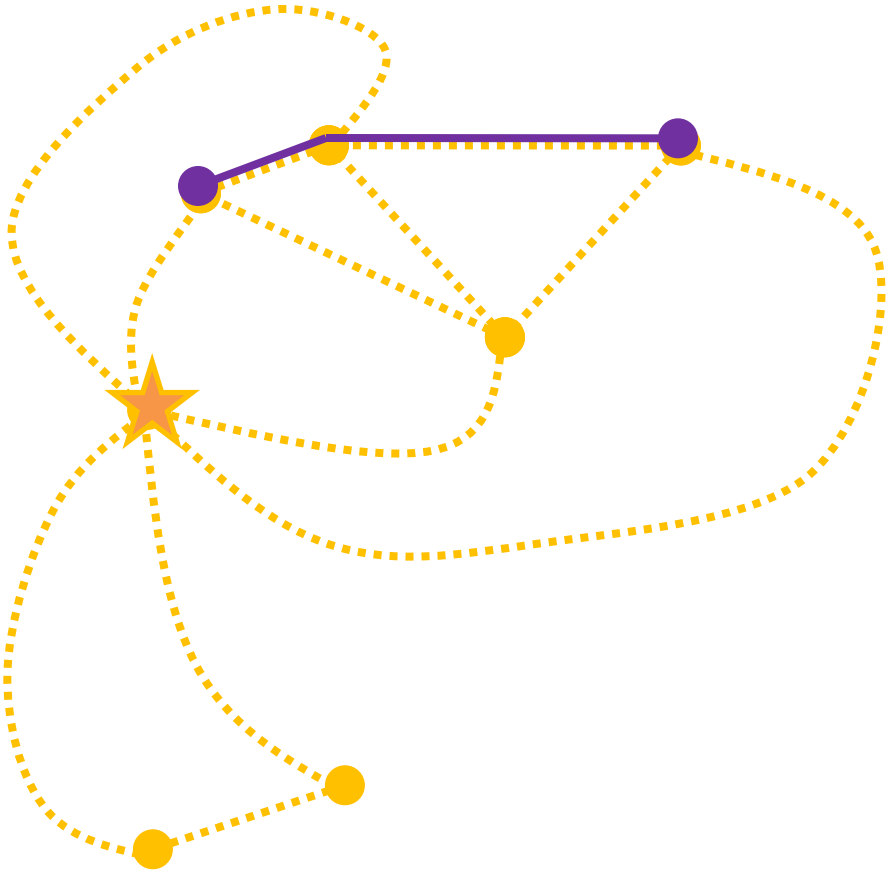
Node Splitting



Edge Removal



Face Graph and Pairing



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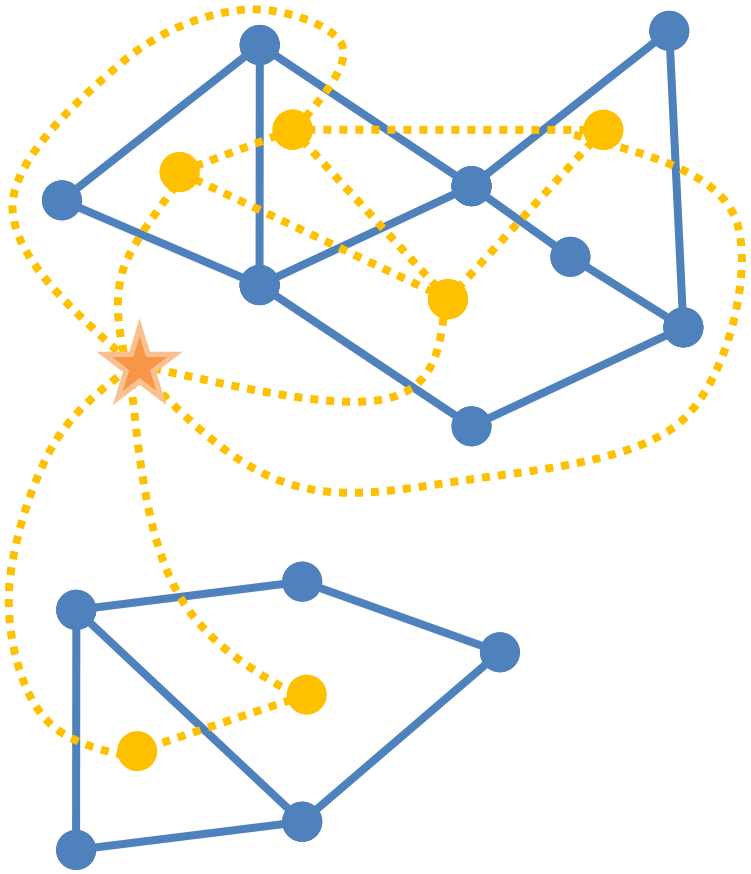
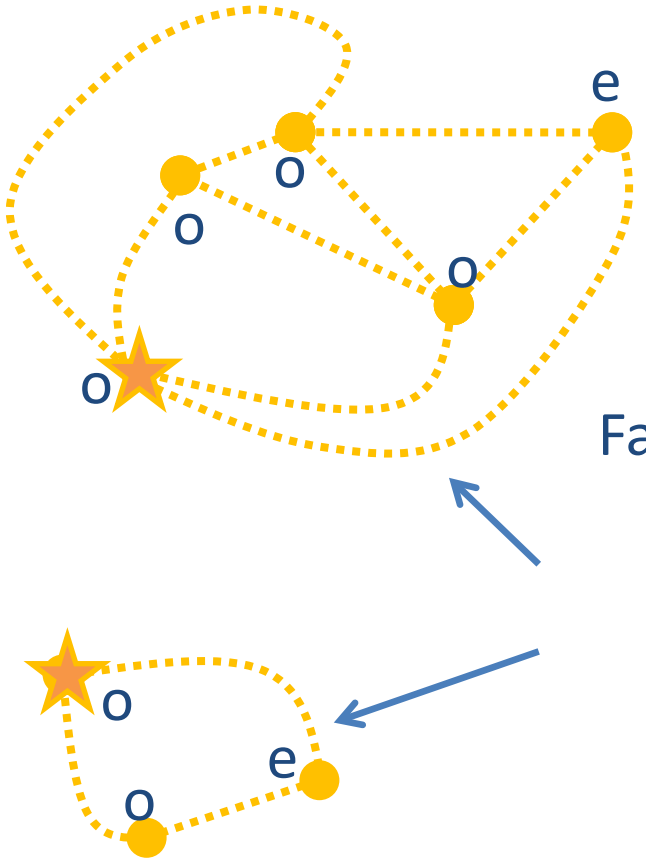
Face Graph Partition

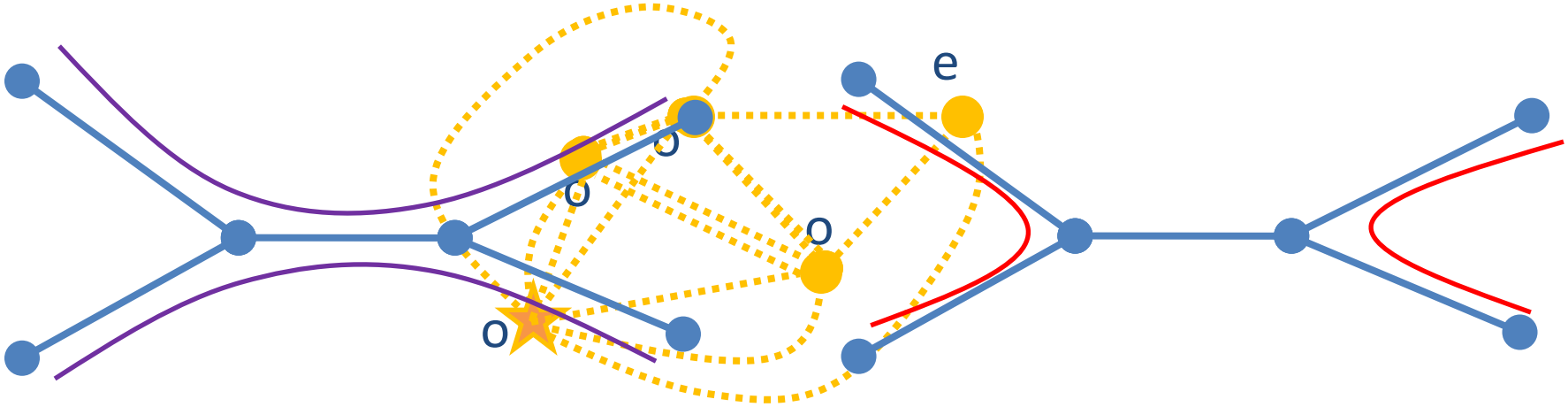




o/e:
Face Node
Polarity

SubFG Simplification

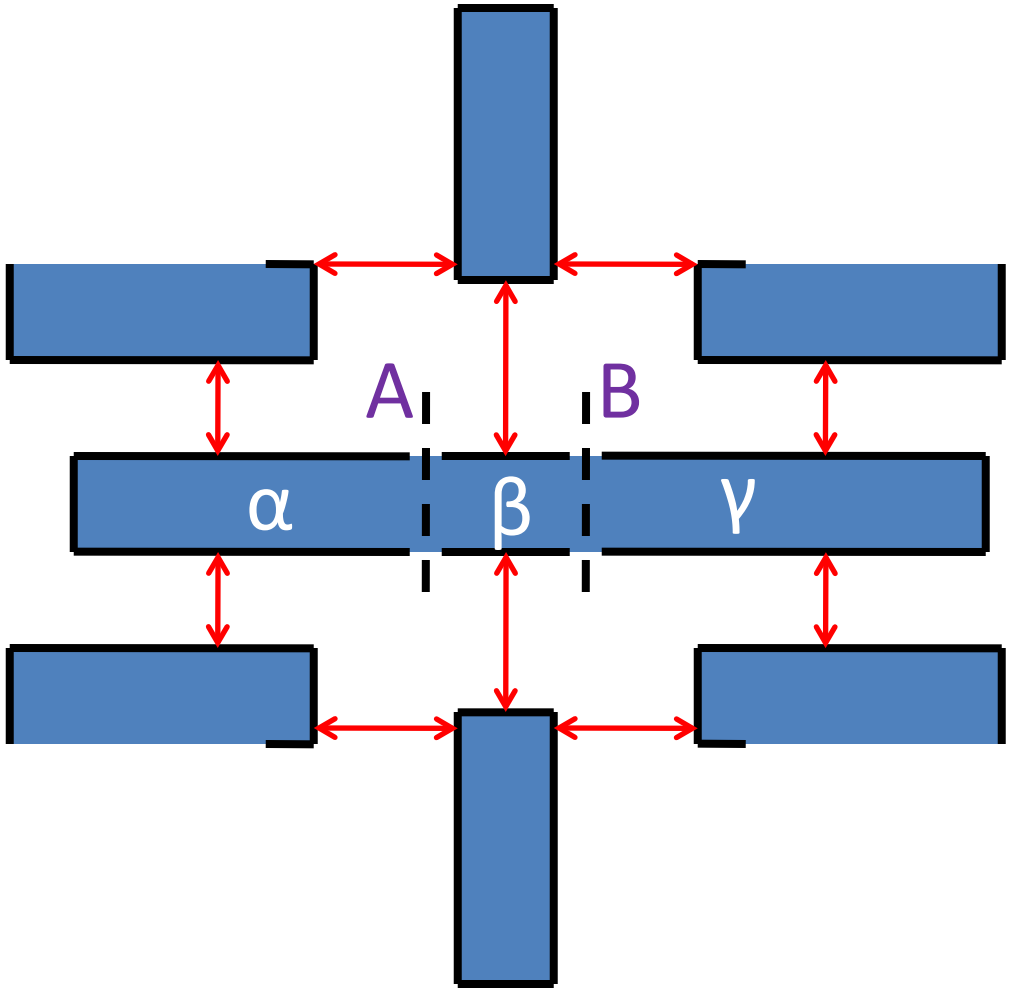
- Only odd face need to be paired
- Use Floyd-Washall algorithm to find the shortest path for each pair of odd nodes
- Create a complete graph called Pairing Cost Graph (PCG)



Matching Based Solution

- The odd vertex pairing in the simplified SubFG is minimum weighted perfect matching problem
- Convert the minimum weighted perfect matching problem by changing edge weight into a maximum weighted matching problem

Dependent Stitch



Layout Pattern

DPL Conflict

Candidate Stitch

Stitch Shield

Contributions

- Prove that Conflict Graph is planar
- Create Face Graph to model two face merging operations
- Propose a new framework for optimal DPL decomposition
- Reduce odd-node pairing problem in the entire FG into a set of sub-problems
- Transform the pairing problem into minimum weighted matching problem
- Use an polynomial runtime maximum weighted matching to solve the minimum weighted matching

Experiment Setup and Result

- Coded in C
- Simulation is run on a 2.8GHz Intel Linux machine with 32GB RAM

	Matching Based Decomposer			Kahng's		
Design	# Stitch	# ER	CPU (s)	# Stitches	# ER	CPU (s)
AES	31	0	4.9	33	0	17.2
TOP-B	11036	652	45.1	14072	800	448.1
TOP-C	68372	3711	214.3	69490	4000	6629
TOP-D	26917	1395	105.8	27908	1600	1228
Comparison	1	1	1	1.05	1.11	23.7

Conclusion and Future Work

- Conflict Graph is Planar
- Matching Based Decomposer
- Optimal and Polynomial Complexity
- Extend the face merging formulation to simultaneously solve DPL decomposition and layout modification